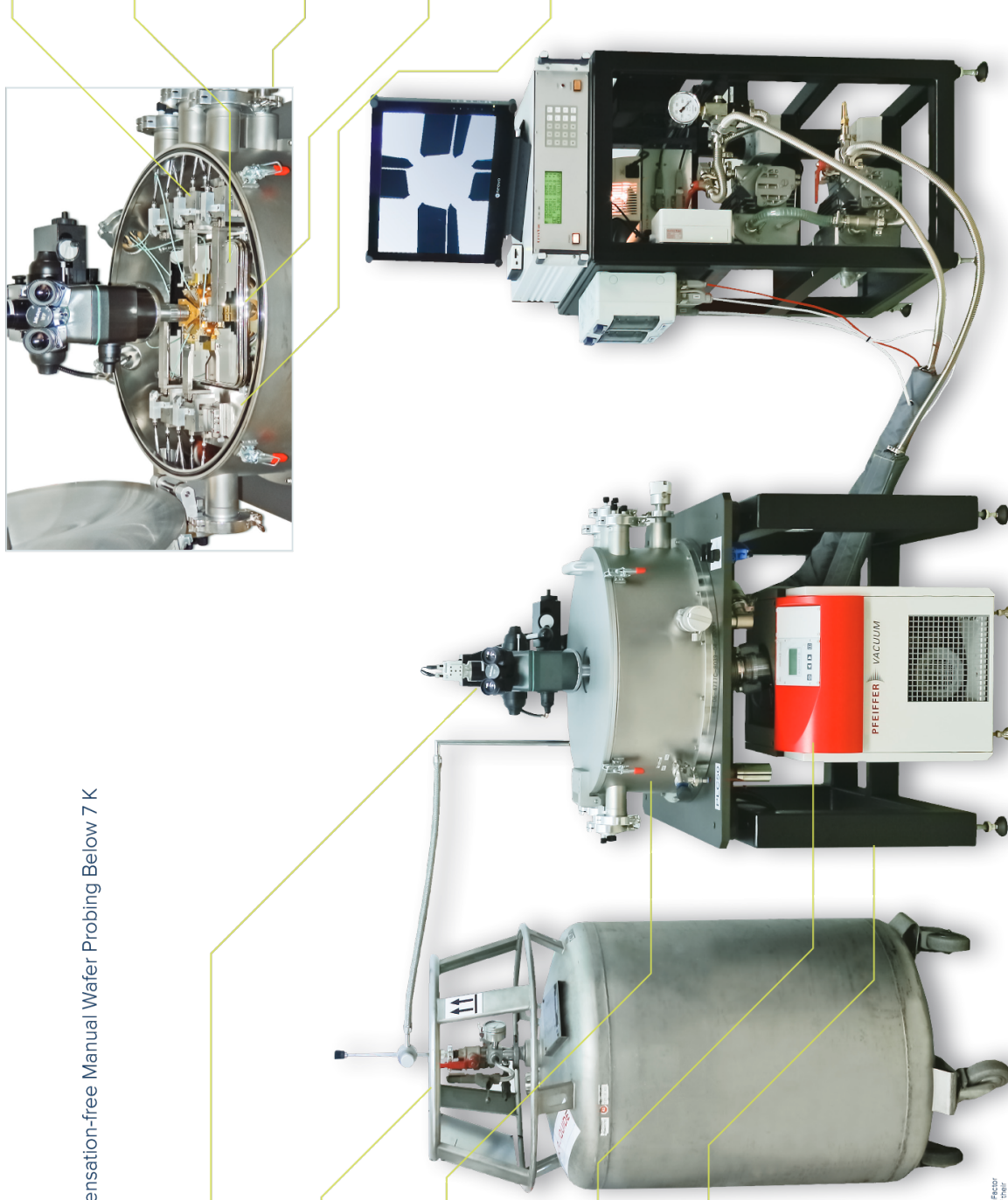


Cascade PLC50

Cost-effective, Ice- and Condensation-free Manual Wafer Probing Below 7 K



Microscope

- Zoom microscope with camera and illumination
- Video monitor

Cryogenic system

- Temperature range <math>< 7\text{ K}</math> to 400 K
- Continuous flow cryostat with supply tank, transfer line and exhaust pumps
- Temperature controller

Vacuum chamber

- Wide pressure range from atmospheric to high vacuum (1E^{-4} mbar)
- Hinged chamber lid for easy access
- Space for cabling and additional electronics inside
- DC and RF electrical feed through flanges

Vacuum control

- High-vacuum pump unit
- Turbo molecular pump directly connected to the chamber

Vibration isolated mainframe

- Pneumatic vibration damping
- Rigid framework and base plate

Positioners

- Inside vacuum chamber for excellent mechanical stability
- Linear backlash-free movement
- Reliable and repeatable contact

Chuck stage

- High-precision, linear two-axis stage for high throughput
- XY travel up to 80 mm
- Easy to control from outside the chamber
- Wafer/sample size up to 100 mm
- Optional triax add-on for accurate measurements over chuck

Measurement setup

- DC and RF configuration
- SIGMA™ integration for excellent measurement accuracy
- Example setup with four RF Probes

Cryogenic shield

- Surrounds cryogenic chuck to limit thermal radiation
- Independent temperature control to eliminate gas and particle condensation

Probe platen

- Contact-separation z-movement for step and repeat capability
- Space for up to six positioners

©Copyright 2018, FormFactor, Inc. All rights reserved. FormFactor and the FormFactor logo are trademarks of FormFactor, Inc. All other trademarks are the property of their respective owners. All information is subject to change without notice.

PLC50-PH-0118

www.formfactor.com